# Li,Cheng-Syun

Institute of NanoEngineering and MicroSystems National Tsing Hua University, Taiwan 30013, R.O.C.

# **E**DUCATION

National Tsing Hua University (NTHU), HsinChu, Taiwan

Ph.D. in NanoEngineering and MicroSystems (MEMS/NEMS), Sep. 2009 – Jan. 2015 (Defense Date: 6, January, 2015)

- Specification on CMOS-integrated micromechanical resonators and oscillators
- Current research project: Capacitively Driving and Piezoresistively Sensing MEMS Resonators

National Taipei University of Technology (NTUT), Taipei, Taiwan

#### M.S. in Mechatronic Engineering (ME), ~Jun. 2008

- Specification on CMOS-MEMS Devices, fabrications, sensor readout circuits, soft magnetic materials
- Master Thesis: Design of Driving Circuit and Chip Layout for the CMOS MEMS Fluxgate Magnetometer

Feng Chia University (FCU), TaiChung, Taiwan

B.S. in Automatic Control Engineering(EE), ~Jun. 2006

- Major in MicroElectroMechanical System (MEMS)
- Specification on Automatic Control and MicroMechanical Sensors

# **PROFESSIONAL INTERESTS**

- Nano/Microelectromechanical Systems
- Semiconductor/MEMS technologies

- Analog and Mixed-signal Circuits
- Sensors and Interface Circuits

# **E**XPERIENCE

Military Service (Obligation)

Taiwan, Air force, Oct. 2008 – Sep. 2009, Air force, Corporal.

Visiting Scholar (financial support by National Science council, 2013)

Electrical Engineering, Case Western Reserve University, Cleveland, OH, U.S., Aug. 2013-May 2014.

Topic: Parametric amplification on the bulk mode resonator

# **PROJECT EXPERIENCE**

Graduate Research Assistant Fall 2009 – Dec. 2014 National Tsing Hua University, HsinChu, Taiwa
---

Advisor: Prof. Sheng-Shian Li

### Foundry RF MEMS SOI resonator platform development. (2009-2012)

- Design many kinds of devices and verify the platform.
- Silicon based piezoresistive resonator and differential measurement for the first time without the need for the post-data processing.
- Design of advanced CMOS-MEMS resonator platform (2009-2011)
  - Overcome the process issues and demonstrate the devices in 0.18 µm CMOS MEMS platform.
- Design of capacitively driving and piezoresistively sensing CMOS-MEMS resonator and oscillator(2011-2014)
  - Piezoresistive based CMOS MEMS resonator target for timing reference and sensors.
  - Record High Q > 15,000 CMOS MSME bulk mode resonator.
  - ► CMOS-MEMS Oscillator with Piezoresistive based resonator.

### Parametric amplification in MEMS resonator (2013-2014)

- ► Parametric amplification on the bulk mode CMOS MEMS resonator.
- ▶ Parametric amplification on the flexure mode CMOS MEMS resonator/oscillator.

Graduate Research Assisant	Fall 2006 – Spring 2008	National Taipei University of	Technology, Taipei, Taiwan
----------------------------	-------------------------	-------------------------------	----------------------------

Advisor: Prof. Jen-Tzong Jeng & Prof. Chih-Cheng Lu

Cell Phone: 886+988033905 (O): 886-3-571-5131-80631

Email: s9835815@m98.nthu.edu.tw

### Design of driving circuit and chip layout for the CMOS MEMS fluxgate magnetometer

- ► Fabricate and measure the characteristics of soft magnetic thin films for fluxgate magnetometers
- Design the interface circuit and sensing system on the PCB for the magnetometer.
- Magnetometer characterization and earth magnetic field measurement
- ► The sensitivity of the magnetometer is about 25.9 V/mT and the linear range is larger than 1 mT with feedback magnetic field. Open loop sensitivity is about 0.47 V/mT with a linear range between ±0.5 mT.

# Chip scale design simulation by Ansoft.

# **PROFESSIONAL SKILLS and EXPERIENCES**

- Computer software: MATLAB, Cadence Virtuoso, ADS, ANSYS, COMSOL, HSPICE, OFFICE...etc.
- MEMS and RF Related Experiences:
  - Network analyzer and spectrum analyzer for MEMS device measurement.
  - Sustaining circuit for MEMS device. (Transimpedance Amplifier, Pierce Oscillator for piezoresistive resonators and Cherry Hooper circuits for the differentially piezoresistive resonator configuration)
  - Earth's magnetic field measurement by using my designed fluxgate magnetometer (Handmade) and circuits. (Master's thesis)
  - Noise of magnetic sensor (fluxgate) measurement by using Lock-in amplifier as a spectrum. (Master's thesis)

#### MEMS Process Experiences:

- Post-CMOS processes: RIE, XeF<sub>2</sub> silicon isotropic etching, Vapor HF, HF for oxide release, Metal wet etching.
- Soft magnetic material thin film deposition (Lithography and PVD) and measure the characteristics.
- Troubleshooting of the magnetic thin film deposition problems as well as investigate and optimize the condition of thin film deposition.
- Assistant for the cleanroom of the school (NTUT) organizing the facilities training and equipment maintenances.

#### Courses Projects

- Hspice, Cadence and matlab simulations for Analog to Digital circuit (ADC), Digital Filter, .etc.
- Phase Lock Loop (PLL) System simulation by Matlab Simulink

### **HONORS AND AWARDS**

	2014 FITI Innovation & Startup Competition: First Stage (Team Leader). Project Title:	2014
CMO	DS-MEMS timing reference for IoTs.	2013
•	2013 Founding of Study Abroad Program	2012
•	2012 IEEE Sensors Conference : Best Student Paper Award (Co-recipient)	2012
•	2012 CIC Outstanding Chip Design Award: Best Design	2012

2012 iNEMS student paper competition: Excellent Research Paper

# Patents

- Sheng-Shian Li, and <u>Cheng-Syun Li</u>, "MEMS resonator, manufacturing method thereof, and signal processing method using MEMS resonator," US Patent Granted, 2014.
- [2] MEMS Oscillator, under review.

### **PUBLICATION: JOURNAL ARTICLES**

- [1] <u>C.-S. Li</u>, M.-H. Li, C.-C. Chen, C.-H. Chin, and S.-S. Li "A Low Voltage CMOS-MEMS Thermal-Piezoresistive Resonator with Q > 10,000," accepted for publication in *IEEE Electron Device Letter*, 2014.
- [2] <u>C.-S. Li</u>, M.-H. Li, and S.-S. Li "Differentially piezoresistive transduction of high-Q encapsulated SOI-MEMS resonators with sub-100nm gaps," *IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control*, vol. 62, no.1, pp. 220–229, Jan. 2015.
- [3] M.-H. Li, C.-Y. Chen, <u>C.-S. Li</u>, C.-H. Chin, and S.-S. Li, "Design and characterization of a dual-mode CMOS-MEMS resonator for TCF manipulation," accepted for publication in IEEE/ASME J. Microelectromech. Syst. (JMEMS)
- [4] C.-H. Chin, <u>C.-S. Li</u>, M.-H. Li, Y.-L. Wang, S.-S. Li, "Fabrication and characterization of a charge-biased CMOS-MEMS resonant gate field effect transistor," *J. Micromech. Microeng.* vol.24, no. 9, 09005, 2014.
- [5] M.-H. Li, C.-Y. Chen, C.-S. Li, C.-H. Chin, and S.-S. Li, "A monolithic CMOS-MEMS oscillator based on an ultra-low-power

ovenized micromechanical resonator," accepted for publication in IEEE/ASME J. Microelectromech. Syst. (JMEMS).

- [6] C.-Y. Chen, M.-H. Li, <u>C.-S. Li</u>, and S.-S. Li, "Design and characterization of mechanically coupled CMOS-MEMS filters for channel-select applications," *Sens. Actuators A*, vol. 216, no. 1, pp. 394-404, Sep. 2014.
- [7] C.-S. Li, M.-H. Li, C.-H. Chin, and S.-S. Li "Differentially piezoresistive sensing for CMOS-MEMS resonators," *IEEE/ASME J. Microelectromech. Syst. (JMEMS)*, vol. 22, no. 6, pp. 1361-1372, Dec. 2013.
- [8] V. Pachkawde, M.-H. Li, <u>C.-S. Li</u>, and S.-S. Li, "A CMOS-MEMS resonator integrated system for oscillator application," *IEEE Sensors Journal*, vol. 13, no. 8, pp. 2882-2889, Aug. 2013.
- [9] <u>C.-S. Li</u>, L.-J. Hou, and S.-S. Li, "Advanced CMOS-MEMS resonator platform," *IEEE Electron Device Letter*, vol. 33, no. 2, pp.272-274, Feb. 2012.

#### **CONFERENCE PROCEEDINGS**

- C.-H. Chin, <u>C.-S. Li</u>, M.-H. Li, and S.-S. Li, "A CMOS-MEMS arrayed RGFET oscillator using a band-to-band tunneling bias scheme," to be presented in the 28th IEEE Int. Micro Electro Mechanical Systems Conf. (MEMS'15), Estoril, Portugal, Jan. 18-22, 2015.
- [2] M.-H. Li, <u>C.-S. Li</u>, and S.-S. Li, "Exploring the *Q*-factor limit of temperature compensated CMOS-MEMS resonators," to be presented in the 28th IEEE Int. Micro Electro Mechanical Systems Conf. (MEMS'15), Estoril, Portugal, Jan. 18-22, 2015.
- [3] M.-H. Li, C.-Y. Chen, C.-H. Chin, <u>C.-S. Li</u>, and S.-S. Li, "Optimizing the close-to-carrier phase noise of monolithic CMOS-MEMS oscillators using bias-dependent nonlinearity," to be presented in the, 2014 IEEE International Electron Devices Meeting (IEDM'14), San Francisco, CA, Dec. 15-17, 2014.
- [4] <u>C.-S. Li</u>\*, J. Lee\*, Z. Wang, M.-H. Li, C.-H. Chin, S.-S. Li, and P. X.-L. Feng "High-Frequency Parametric Bulk Mode Resonators in CMOS-MEMS Technology," *Proceedings*, 2014 Joint Conf. of the IEEE Int. Frequency Control Symp. Taipei, Taiwan, May 19-22, 2014, pp. 329-331. (\*Co-first authors)
- [5] <u>C.-S. Li</u>\*, J. Lee\*, M.-H. Li, C.-H. Chin, S.-S. Li, and P. X.-L. Feng "Multimode Characteristics of High-Frequency CMOS-MEMS Bulk-Mode Resonators," *Proceedings*, 2014 Joint Conf. of the IEEE Int. Frequency Control Symp. Taipei, Taiwan, May 19-22, 2014, pp. 478-480. (\*Co-first authors)
- [6] C.-Y. Chen, M.-H. Li, C.-H. Chin, <u>C.-S. Li</u>, and S.-S. Li, "Combined electrical and mechanical coupling for mode-reconfigurable CMOS-MEMS filters," Proceedings, 27th IEEE Int. Micro Electro Mechanical Systems Conf. (MEMS'14), San Francisco, CA, Jan. 26-30, 2014, 1249-1252.
- [7] M.-H. Li, C.-Y. Chen, <u>C.-S. Li</u>, C.-H. Chin, C.-C. Chen, and S.-S. Li, "Foundry-CMOS integrated oscillator circuits based on ultra-low power ovenized CMOS-MEMS resonators," 2013 IEEE International Electron Devices Meeting (IEDM'13), Washington, DC, Dec. 9-11, 2013.
- [8] <u>C.-S. Li</u>, M.-H. Li, C.-H. Chin, C.-Y. Chen, P. X.-L. Feng, and S.-S. Li "A Piezoresistive CMOS-MEMS Resonator with High Q and Low TC<sub>f</sub>," *Proceedings*, 2013 IEEE UFFC Joint Symposia, Prague, Czech Republic, July 21-25, 2013, pp. 425-428.
- [9] M.-H. Li, C.-Y. Chen, <u>C.-S. Li</u>, C.-H. Chin and S.-S. Li, "Enhanced temperature sensitivity of a single CMOS-MEMS resonator via resonant modes in orthogonal axes," *Proceedings*, 2013 IEEE UFFC Joint Symposia, Prague, Czech Republic, July 21-25, 2013.
- [10] C.-H. Chin, <u>C.-S. Li</u>, M.-H. Li, and S.-S. Li, "A CMOS-MEMS resonant-gate transistor," *Dig. of Tech. Papers*, the 17th Int. Conf. on Solid-State Sensors & Actuators (Transducers'13), Barcelona. Spain, June 16-20, 2013, pp. 2284-2287.
- [11] C.-Y. Chen, M.-H. Li, <u>C.-S. Li</u>, and S.-S. Li, "Design and characterization of mechanically-coupled CMOS-MEMS filters," *Dig. of Tech. Papers*, the 17th Int. Conf. on Solid-State Sensors & Actuators (Transducers'13), Barcelona. Spain, June 16-20, 2013, pp. 2288-2291.
- [12] H. Zhu, C.-H. Chuang, <u>C.-S. Li</u>, M.-H. Li, J. E.-Y. Lee, and S.-S. Li, "The effects of tight capacitive coupling on phase noise performance: A LAMÉ-mode MEMS oscillator study," *Dig. of Tech. Papers*, the 17th Int. Conf. on Solid-State Sensors & Actuators (Transducers'13), Barcelona. Spain, June 16-20, 2013, pp. 2304-2307.
- [13] T.-T. Chen, J.-C. Huang, Y.-C. Peng, C.H. Chu, C.-H. Lin, C.-W. Cheng, <u>C.-S. Li</u>, S.-S. Li, "A 17.6-MHz 2.5V ultra-low polarization voltage MEMS oscillator using an innovative high gain-bandwidth fully differential transimpedance voltage amplifier," *Proceedings*, 26th IEEE Int. Micro Electro Mechanical Systems Conf. (MEMS'13), Taipei, Taiwan, Jan. 20-24, 2013.
- [14] M.-H. Li, <u>C.-S. Li</u>, C.-H. Chin, C.-Y. Chen, and S.-S. Li, "An ultra-low power ovenized CMOS-MEMS resonator monolithically integrated with interface circuits," *Proceedings*, 26th IEEE Int. Micro Electro Mechanical Systems Conf. (MEMS'13), Taipei,

Taiwan, Jan. 20-24, 2013.

- [15] V. Pachkawde, <u>C.-S. Li</u>, S.-S. Li, "A fully-differential CMOS-MEMS resonator integrated with an On-chip Amplifier", *IEEE SENSORS 2012 October 28-31, 2012 Taiwan.* (Best Student Paper Award)
- [16] <u>C.-S. Li</u>, M.-H. Li, and S.-S. Li "Differential measurement of piezoresistive transduction for silicon-based MEMS resonators", *Proceedings*, 2012 Joint Conf. of the IEEE Int. Frequency Control Symp. Baltimore, Maryland, USA, May 21-24, 2012,
- [17] M.-H. Li, <u>C.-S. Li</u>, L.-J. Hou, Y.-C. Liu and S.-S. Li, "A 1.57mW 99dBOhm CMOS transimpedance amplifier for VHF micromechanical reference oscillators," *Proceedings*, the 2012 IEEE Int. Symp. on Circuits and Systems (*ISCAS'12*), Seoul, Korea, May 20-23, 2012
- [18] C.-S. Li, C.-H. Chin, Y.-C. Liu, and S.-S. Li, "Capacitively-driven and piezoresistively-sensed CMOS-MEMS resonators", *Proceedings*, 25rd Int. IEEE Micro Electro Mechanical Systems Conf. (*MEMS'12*), Paris, France, Jan. 29-Feb. 2, 2012, pp. 539-542.
- [19] L.-J. Hou, <u>C.-S. Li</u> and S.-S. Li, "High-stiffness-driven micromechanical resonator oscillator with enhanced phase noise performance", *Proceedings*, 25rd Int. IEEE Micro Electro Mechanical Systems Conf. (*MEMS'12*), Paris, France, Jan. 29-Feb. 2, 2012, pp. 700-703.
- [20] C.-S. Li and S.-S. Li, "Capacitive gap-aspect-ratio enhancement using advanced CMOS process for CMOS-MEMS resonators," *Proceedings*, 9th International Workshop on High Aspect Ratio Micro Structure Technology (HARMST'11), Hsinchu, Taiwan, June 12-18, 2011, pp. 47-48.

# **D**OMESTIC PUBLICATIONS

- [1] 陳昭瑜、李銘晃、<u>李承勳</u>、李昇憲, "機械耦合式 CMOS-MEMS 濾波器之設計與特性探討,"第17 屆奈米工程暨微系統技術研討會, 台中, Aug. 22-23, 2013. (Oral Presentation)
- [2] 莊捷旭、<u>李承勳</u>、李銘晃、李昇憲,"高 Q 值微機械震盪器研製與探討差動機制對微機械震盪器的影響,"第17 屆奈米工程暨微系統技術研 討會,台中,Aug. 22-23, 2013. (Oral Presentation)
- [3] <u>C.-S. Li</u>, C.-C. Lu, J.-T. Jeng, "Characteristics of soft magnetic thin films for integrated fluxgate magnetometers", Annual Meeting of the physical Society of Republic of China, Hsinchu, PC-21, Jan. 2008.
- [4] <u>C.-S. Li, C. C. Lu</u>, and J. T. Jeng, "Designs of Driving Circuit and Chip Layout for the CMOS-MEMS Fluxgate Magnetometer" 97 年台灣磁性技術 協會年會暨第二十屆磁學與磁性技術研討會, 2008.7.1.
- [5] 李承勳、陳亭宏、鄭振宗、呂志誠, "繞線式磁通開磁量計之製作與特性測定",第25屆中國機械工程學會學術研討會,台灣彰化,十 一月,(2008),編號0953。

Teaching Assistant	Fall 2010– Spring 2012	National Ts	ing Hua University, HsinChu, Taiwan
► Undergraduate-level course: PME 3202 – <i>Electronics II</i>			2012 Fall
► Graduate-level course: NEMS	► Graduate-level course: NEMS5110 – Measurements of nano and micro devices		
<ul> <li>Undergraduate-level course: F</li> </ul>	► Undergraduate-level course: PME 3202 – <i>Electronics II</i>		2011 Fall
► Graduate-level course: PME 5	► Graduate-level course: PME 5101 – Microsensor and Microinstrument System		2011 Spring
► Graduate-level course: NEMS5800 – <i>RF MEMS Theory and Applications</i>		2010 Fall	
Teaching Assistant	2007 N	Vational Taipei Unive	ersity of Technology, Taipei, Taiwan
Micro- and Nano System Lab	of NTUT (Common Lab Assistant)		2007

# LANGUAGES

English - Listening/ Reading/ Speaking/ Writing

Mandarin - Listening/ Reading/ Speaking/ Writing (Native speaker)

### **PROFESSIONAL AFFILIATIONS**

IEEE, Student member

# Reference

2011-Present

Dr. Sheng-Shian Li (Ph.D thesis Advisor) Email : ssil@mx.nthu.edu.tw Dr. Jen-Tzong Jeng (Master thesis Advisor) Email : jtjeng@cc.kuas.edu.tw Last updated on Dec. 23, 2014